

# ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

Stylesheet Version v18.0

## Title of Invention

SAMPLE MOUNT FOR PERFORMING SPUTTER-DEPOSITION  
IN A FOCUSED ION BEAM (FIB) TOOL

Application Number : 12/604,272

Confirmation Number:

First Named Applicant: Lawrence Fischer

Attorney Docket Number: FIS920030137

Art Unit: 1753

Examiner: Ver Steeg

Search string: ( 5434422 or 5635836 or 5922179 or 6407850 or 20020005492 or 20020050565  
.pn

## US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

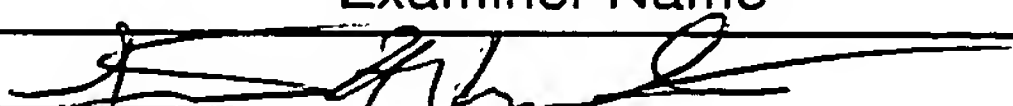
init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
SHV	1	5434422	1995-07-18	Iwamoto et al.		250	491.1
SHV	2	5635836	1997-06-03	Kirtley et al.		324	262
SHV	3	5922179	1999-07-13	Mitro et al.		204	298.04
SHV	4	6407850	2002-06-18	Rojo et al.		359	290

## US Published Applications

Note: Applicant is not required to submit a paper copy of cited US Published Applications

init	Cite.No.	Pub. No.	Date	Applicant	Kind	Class	Subclass
SAV	1	20020005492	2002-01-17	Hashikawa et al.		250	442.11
SHV	2	20020050565	2002-05-02	Tokuda et al.		250	310

## Signature

Examiner Name	Date
	March 11, 2005